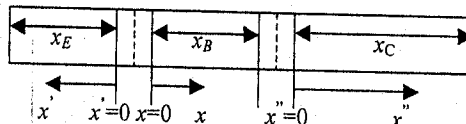


- (4%) 畫出 energy band diagram ( $E_C, E_V, E_F$ ) for a Si p-n junction in thermal equilibrium.
  - (8%) 請指出 Depletion (transition) region 與 neutral region. 並在 energy band diagram 上之適當位置用“電子及電洞”繪出其 Diffusion 的方向。
  - (4%) 最後說明原因在 thermal equilibrium 時 p-端的電洞不會因擴散原理(高濃度的往低濃度擴散)往 n-端擴散。
- (16%) To measure the carrier concentration directly, the most common used method is the Hall Effect. Consider a p-type semiconductor sample (size is  $L \times H \times W$ ), try to set up the measurement (畫出測量的接法與外加電壓電場磁場的方向等) and write the equations to obtain carrier concentration.
- (18%) From Poisson's equation to derive (推導) electric-field distribution and find the maximum field in an abrupt p-n junction. Assumed the metallurgical junction is located at  $x = 0$ , the depletion region in p-side and n-side are  $-x_p$  and  $x_n$ , respectively. Dielectric constant is  $\epsilon_s$ .

4. (a) (10%) A silicon npn bipolar transistor is uniformly doped and biased in the forward-active region. The neutral base width is  $x_B = 0.8 \mu\text{m}$ . The transistor doping concentrations are  $N_E = 5 \times 10^{17} \text{ cm}^{-3}$ ,  $N_B = 10^{16} \text{ cm}^{-3}$ , and  $N_C = 10^{15} \text{ cm}^{-3}$ . For  $V_{BE} = 0.625 \text{ V}$ , determine  $n_B$  at  $x = 0$  and  $p_B$  at  $x = 0$ . Note that  $n_i = 1.5 \times 10^{10} \text{ cm}^{-3}$ ,  $V_t = kT/q = 0.0259 \text{ V}$ , and  $e^{24.131} = 3.02 \times 10^{10}$ .



- (10%) Consider a uniformly doped silicon bipolar transistor with a metallurgical base width of  $0.5 \mu\text{m}$  and a base doping of  $N_B = 10^{16} \text{ cm}^{-3}$ . The punch-through voltage is to be  $V_{PT} = 25 \text{ V}$ . Determine the collector doping and collector width to meet the punch-through voltage specification. Note that  $\epsilon_{\text{Si}} = 11.7 \times 8.85 \times 10^{-14} \text{ F/cm}$ .
- (10%) Consider an  $n^+$  polysilicon gate and a p-type silicon substrate doped to  $N_a = 3 \times 10^{16} \text{ cm}^{-3}$ . Assume the fixed charge at the oxide-semiconductor interface is  $Q_{ss} = 10^{11} \text{ cm}^{-2}$ . Determine the work function difference  $\phi_{ms}$ . Note that  $n_i = 1.5 \times 10^{10} \text{ cm}^{-3}$ , the bandgap energy  $E_g = 1.12 \text{ eV}$ , and the electron affinity  $\chi = 4.01 \text{ V}$ .
    - (10%) Follow (a). Determine the oxide thickness such that the threshold voltage  $V_{TN} = +0.6 \text{ V}$ . Note that  $V_t = kT/q = 0.0259 \text{ V}$ , and  $\ln(N_a/n_i) = 14.5086$ .
  - (10%) Using superposition, the shift in the flat-band voltage  $\Delta V_{FB}$  due to a fixed charge distribution  $\rho(x) = (a \times x) \text{ C/cm}^3$  in the oxide can be given by  $\Delta V_{FB} = f(\epsilon_{ox}, t_{ox}, a)$ . Please find the function  $f(\epsilon_{ox}, t_{ox}, a)$ , which is a function of the oxide permittivity  $\epsilon_{ox}$ , the oxide thickness  $t_{ox}$ , and the charge distribution coefficient  $a$ .